Atty. Docket No. OSP-10057

PATENTS



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Takeo MATSUKI et al.

Confirmation No. 4114

Serial No. 09/764,880

GROUP 2818

Filed January 23, 2001

Examiner Thinh T. Nguyen

SEMICONDUCTOR DEVICE STRUCTURE AND METHOD FOR MANUFACTURING THE SAME

AMENDMENT

Commissioner for Patents

Washington, D.C. 20231

Sir:

Responsive to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the above-identified application as follows to the Official Action of April 1 20 please amend the April 1 20 plea

IN THE CLAIMS:

Amend claim 1 as follows:

--1. (amended) A structure for a semiconductor device, provided with a contact plug, which is formed by forming a contact hole through a first interlayer insulating film on a silicon substrate and by filling the contact hole with silicon, comprising:

a silicide pad formed on the top surface of the silicon contact plug in a self-aligning manner with said silicon contact plug and having a diameter which is larger than that of the silicon contact plug;

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